Development of a System for Characterisation for a new DEPFET Device

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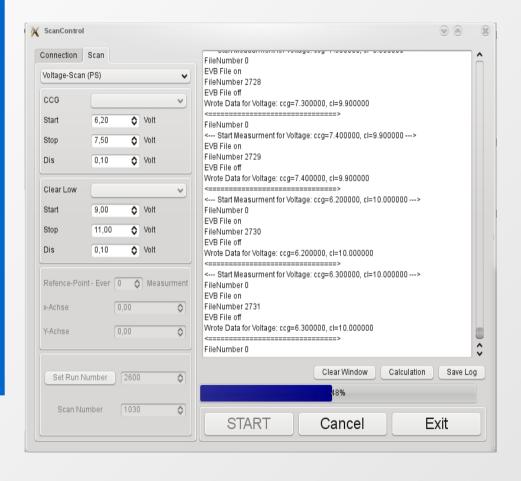
Barcelona, 7/8 October 2009



Motivation

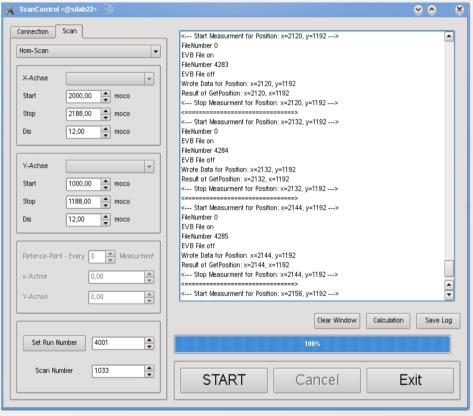
- Repeated characterisation of DEPFET devices requires a system for automatic control and data processing:
 - Voltage control for parameter optimisation (mainly Clear_Low/High, CCG) with ²⁴¹Am-source.
 - Position control for laser measurements, homogeneity scan of whole matrix (gain variations)
 - DAQ control for synchronous data taking

Parameter-Scan



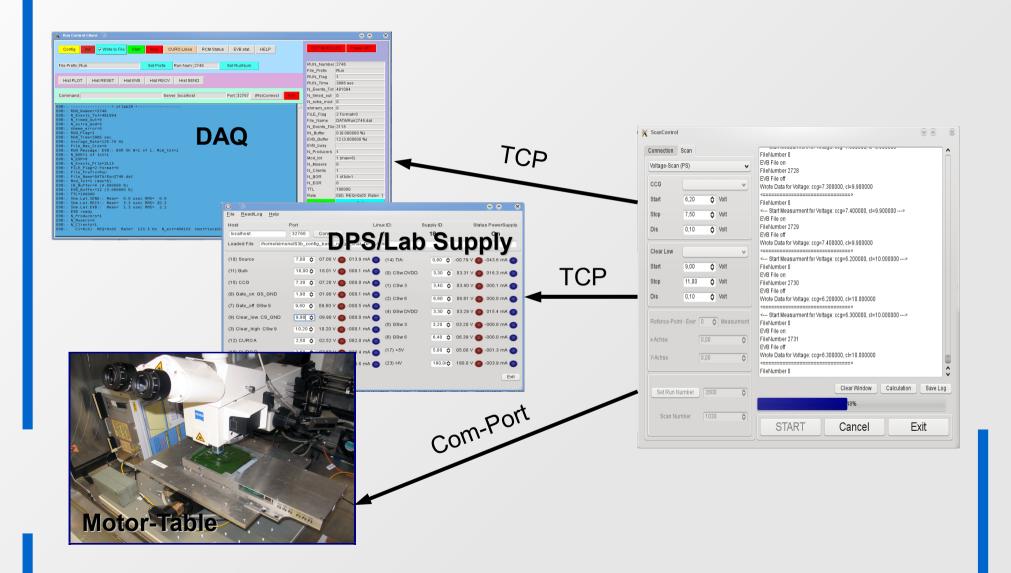
Voltage-Scan:
Clear_Low and CCG
4V range
at a precision of 0.25 V
~ 256 Runs needed
at a precision of 0.1 V
more than 1000 Runs
needed

Homogeneity-Scan

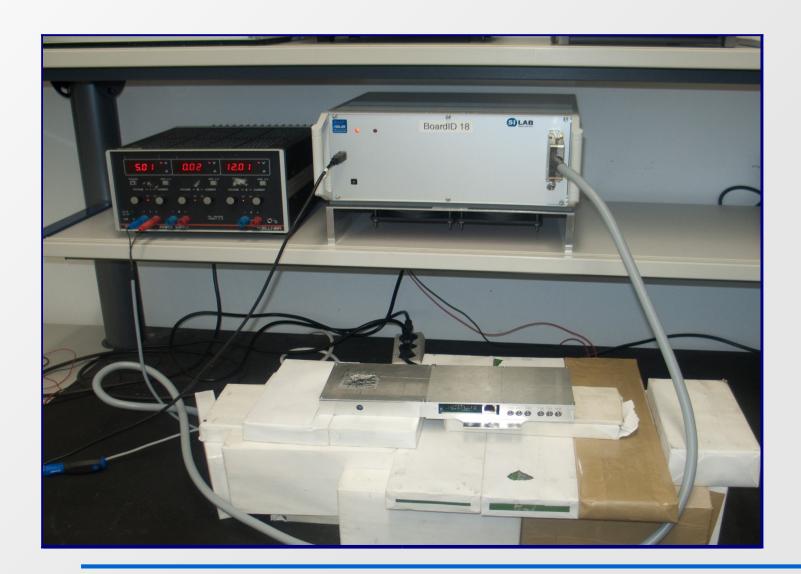


Area-Scan:
 at a precision of 72 µm a
 scan of whole matrix
 would need ~ 2000 Runs
 (~1500 Events/Run)

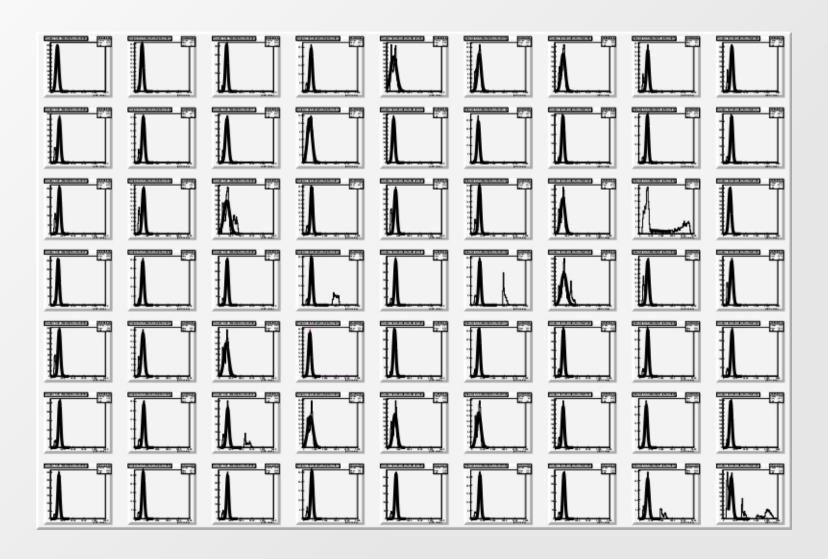
Communication with System



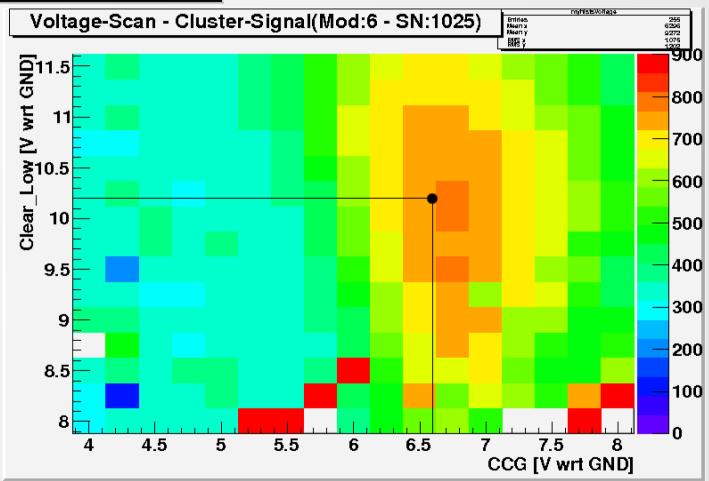
Setup for parameter-Scans



Sample of histograms for voltage-scan (241 Am)

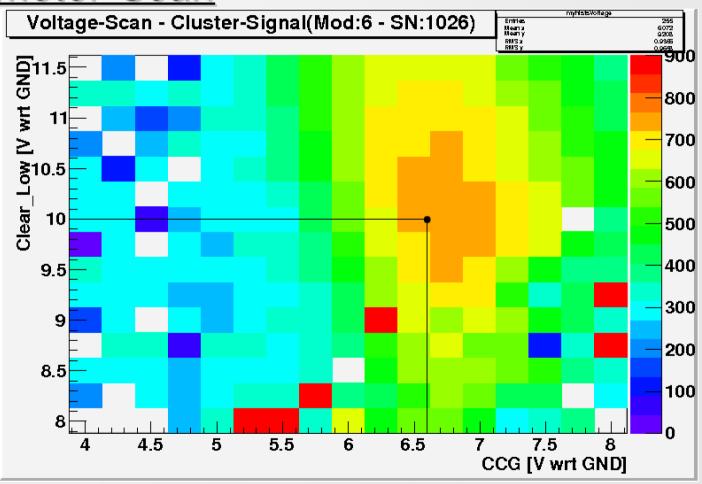


H 3.0.12 (COCG L B) - Telescope Module Parameter-Scan



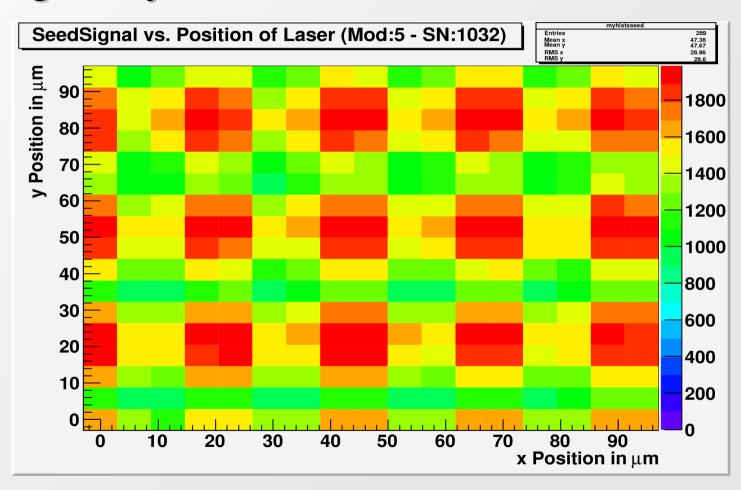
black point: Characterisation results from munich

H 3.0.11 (COCG L B) - Telescope Module Parameter-Scan



black point: Characterisation results from munich

H 3.0.12 (COCG L B) - Telescope Module Homogeneity-Scan



(Pixelsize: 24µm x 32µm)

<u>Summary</u>

- fast and automatic scans of parameters and homogeneity of the DEPFET matrices are possible now
- within 3 hours one can have optimised voltages of a matrix (depending on computer power and precision)